

A B S T R A C T

A BIMORPH MIRROR WITH TWO PIEZOELECTRIC LAYERS SEPARATED
BY A CENTRAL CORE OF SEMIRIGID MATERIAL

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The invention relates to a bimorph mirror presenting
first and second layers (1, 2) of piezoelectric ceramic
together with at least one electrode enabling at least
one curvature of the mirror to be varied as a function of
10 at least one electrical voltage applied to the
piezoelectric ceramics. The mirror of the invention is
characterized in that the first and second layers (1, 2)
are separated by a central core (5) of material such as
glass or silica, forming a semirigid beam.

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Translation of the title and the abstract as they were when originally filed by the
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